

ABSTRACT OF THE DISCLOSURE

A method and apparatus are provided that make it possible to speedily measure, and obtain images of, the three-dimensional distribution of electric fields in integrated circuits, using electro-optic sampling. The sampling is performed using a plurality of electric field sensors, each comprising an electro-optic crystal layer, a light-reflecting layer that is in close contact with the electro-optic crystal layer, and a separation layer that is in close contact with the reflection layer, separating the reflection layer from the object to be measured.